Measurement on electron transport via nanomechanical electron shuttle

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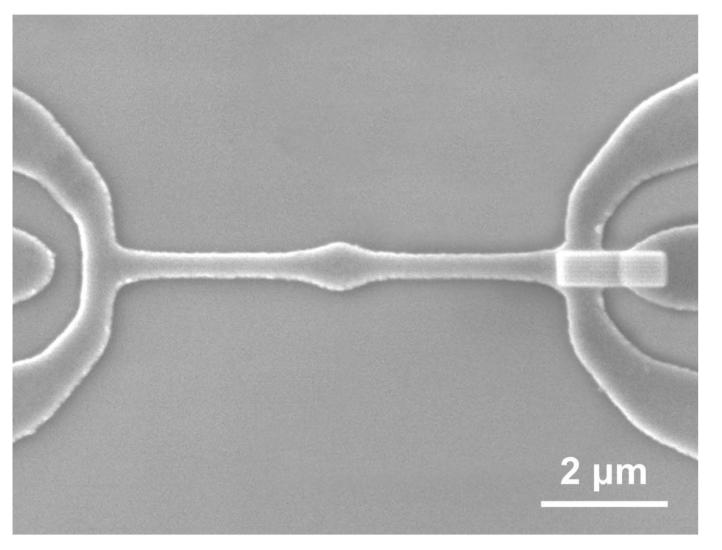
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Abstract

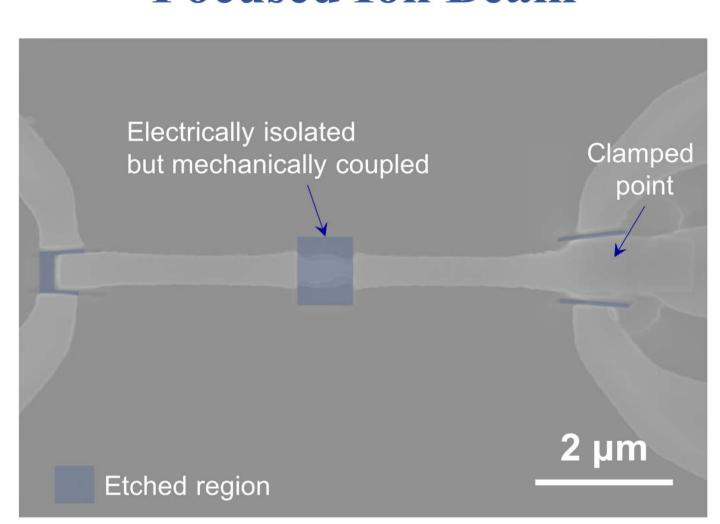
We realized a nanomechanical electron shuttle which consists of a metallic island on a cantilever. This nano mechanical pendulum was fabricated on a SiO₂/Si substrate using conventional semiconductor fabrication processes. The metallic island is externally driven to oscillate between source and drain electrodes due to the cantilever motion in an in-plane flexural mode . The upper part of the cantilever was excited by applying an AC voltage between two electrodes on the left and right hand sides of the cantilever. The shuttling current was observed with the application of a bias voltage between the source and drain electrodes.

Device Fabrication

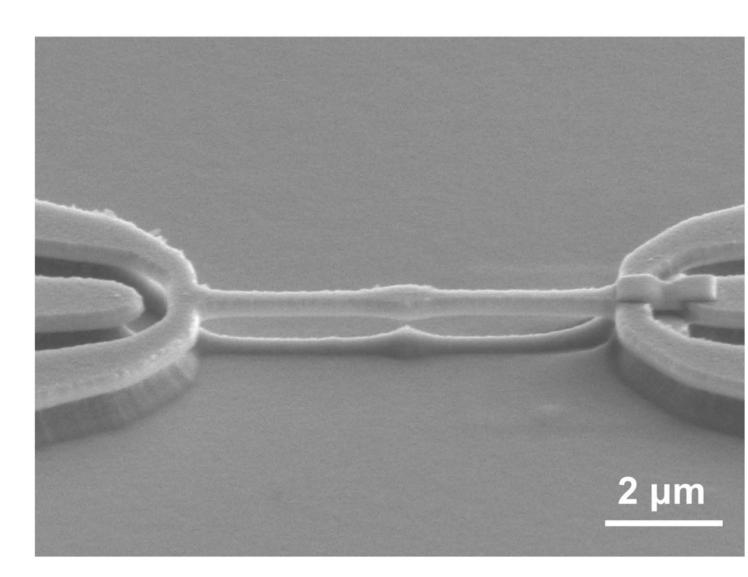
Photolithography Electrode Deposition



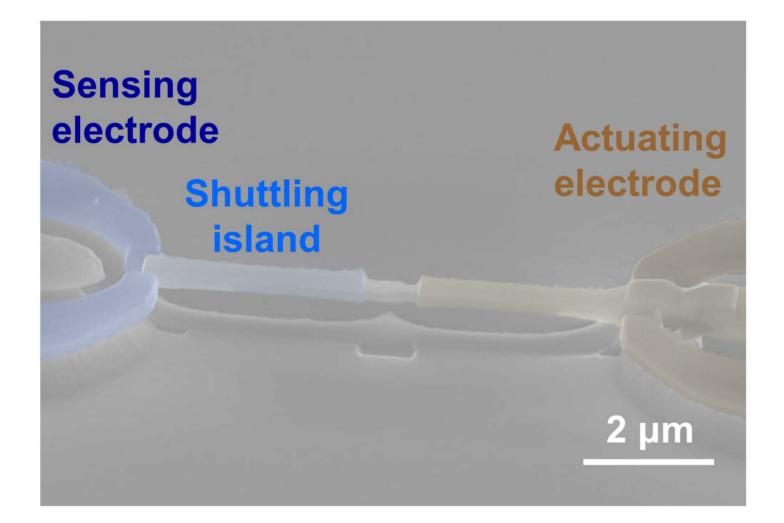
3. Selective Etching with Focused Ion Beam



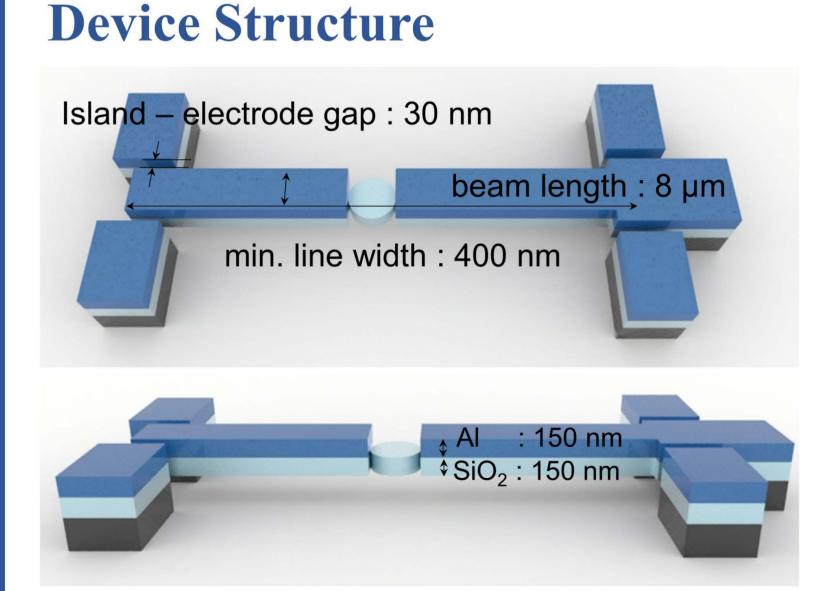
2. Reactive Ion etching



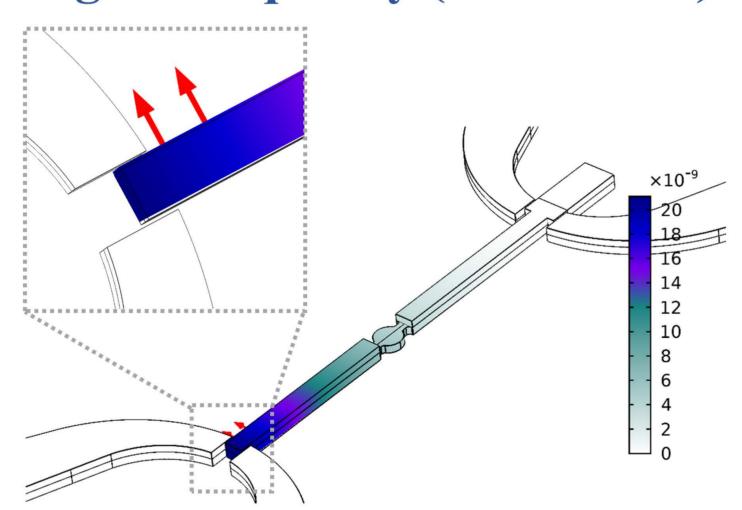
4. Fabrication Result of NEM electron shuttle



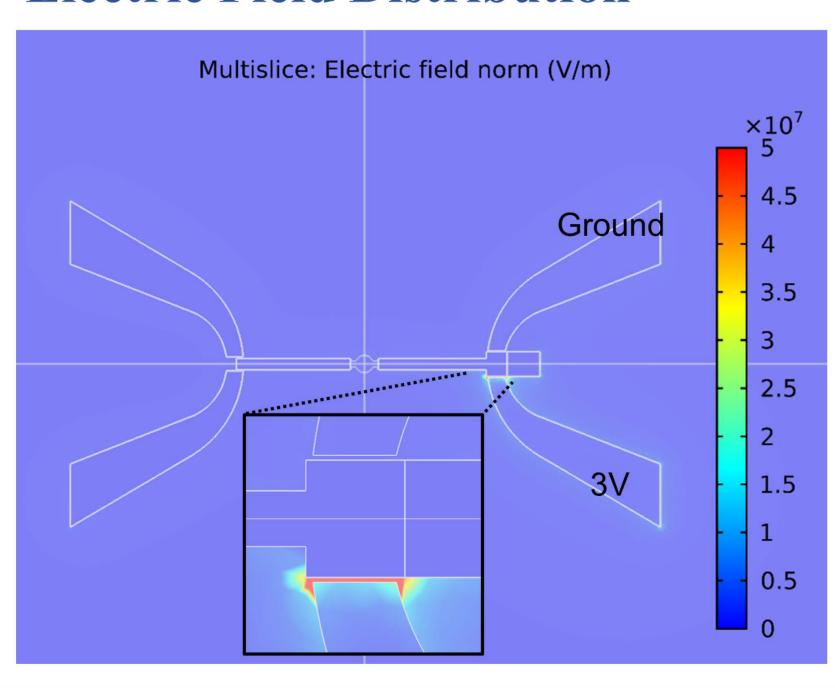
Finite Element Model Analysis



Eigen Frequency (3.774 MHz)

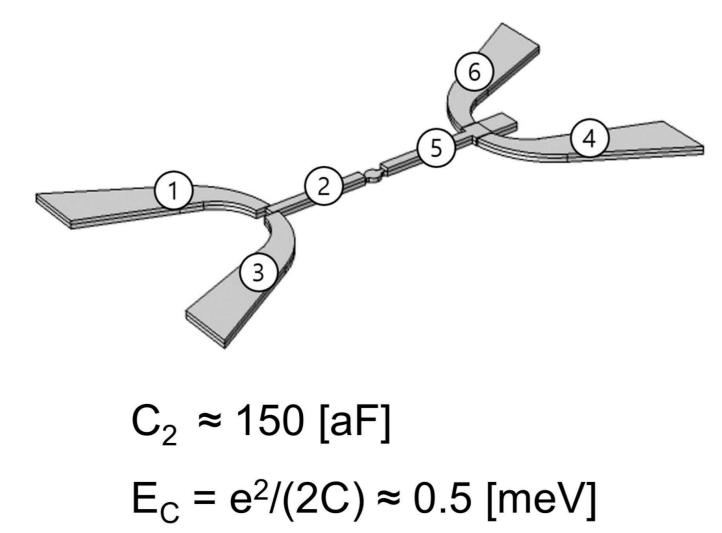


Electric Field Distribution



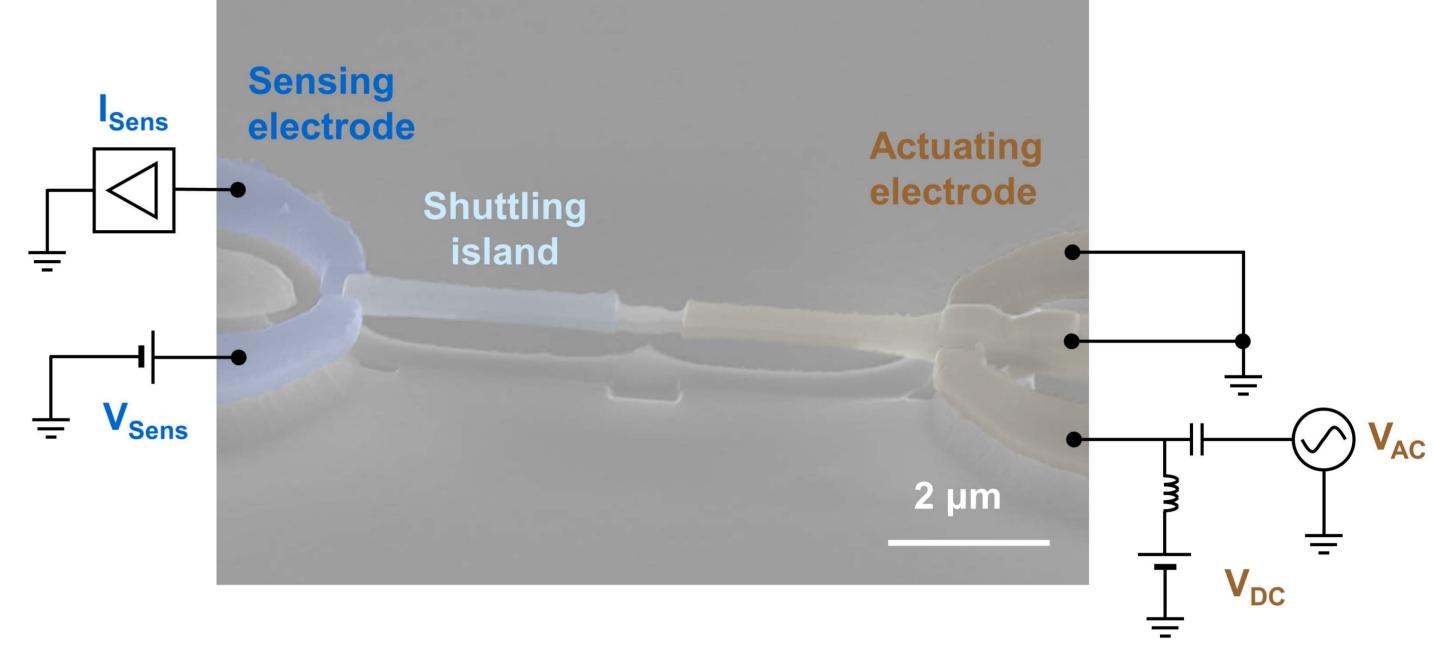
Capacitance

T≈6 [K]

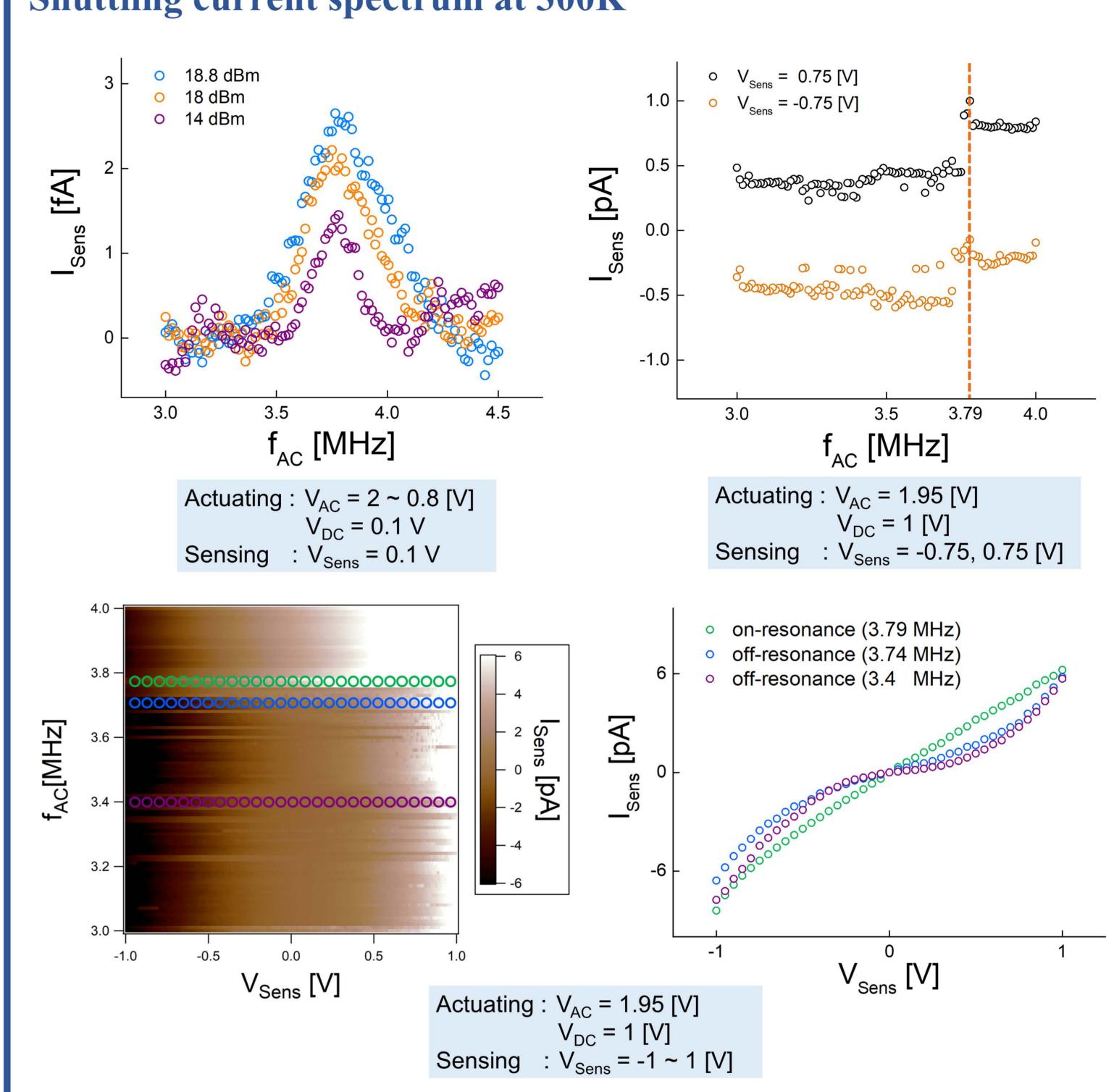


Measurement Setup & Results

AC/DC Measurement in Vacuum Chamber (~10-6 Torr)



Shuttling current spectrum at 300K



Future work

- Perform electron transport measurement at low temperature
- Measure the supercurrent below its critical temperature
- Observe nanowire's mechanical motion due to self-excitation and measure the shuttling current

